

US005825020A

United States Patent [19]

Hansma et al.

[11] Patent Number: 5,825,020 [45] Date of Patent: Oct. 20, 1998

[54]	ATOMIC FORCE MICROSCOPE FOR
	GENERATING A SMALL INCIDENT BEAM
	SPOT

[75] Inventors: Paul K. Hansma, Goleta; Tilman E. Schaffer, Santa Barbara; Jason P.

Cleveland, Ventura, all of Calif.

[73] Assignee: **The Regents of the University of California**, Oakland, Calif.

[21] Appl. No.: 709,349

[22] Filed: **Sep. 6, 1996**

[51] **Int. Cl.**⁶ **G01B 5/28**; H01J 3/14 [52] **U.S. Cl.** **250/216**; 250/234; 250/306;

73/105

[56] References Cited

U.S. PATENT DOCUMENTS

4,935,634	6/1990	Hansma et al	
5,017,010	5/1991	Manin et al	356/345
5,144,833	9/1992	Amer et al	73/105
5,164,791	11/1992	Kubo et al	
5,172,002	12/1992	Marshall .	
5,206,702	4/1993	Kato et al	
5,231,286	7/1993	Kajimura et al	
5,260,824	11/1993	Okada et al	
5,291,775	3/1992	Gamble .	
5,298,975	3/1994	Khoury et al	
5,388,452	2/1995	Harp et al	250/306
5,394,741	3/1995	Kajimur aet al	
5,560,244	10/1996	Prater et al	250/306
5,616,916	4/1997	Handa et al	250/306
5,627,365	5/1997	Chiba et al	250/306
5,672,816	9/1997	Park et al	250/306

OTHER PUBLICATIONS

Drake et al.: "Imaging crystals, polmers and processes in waters with the atomic force microscope." *science* vol. 243, 1586 (1989) (no month).

Hansma et al.: "A new, common optical-lever based atomic force microscope, " *J.Appl.Phys.*, vol. 76, 796 (1994) (no month).

Clark et al.: "A high performance scanning force microscope head design," *Rev.Sci.Instrum.*,vol. 64, No. 4,904 (1993) (no month).

Baselt, et al.: "Scanned-cantilever atomic force microscope head desig," *Rev.Sci.Instrum.*, vol. 64,No. 4, 908 (1993) (no month).

(List continued on next page.)

Primary Examiner—Edward P. Westin Assistant Examiner—John R. Lee Attorney, Agent, or Firm—Fulbright & Jaworski

[57] ABSTRACT

An atomic force microscope utilizing an optical system having a numerical aperture sufficient with the wavelength of light of an incident beam to form a spot on the cantilever having a size of 8 μ m or less in at least one dimension. An adjustable aperture can be utilized to control the size and/or shape of the incident beam spot on the cantilever. Portions of the incident beam and the beam reflected from the cantilever overlap and are directed so that the plane of focus of the incident beam is parallel to the plane of the cantilever. The incident and reflected light beams are separated by polarization using a beamsplitter in conjunction with a quarterwave plate. Focussing can be accomplished with a confocal viewing system coupled with a translatable focusing lens common to the optical system and viewing system. The atomic force microscope enables use with a plurality of cantilevers on the same chip wherein the focus of the incident beam is shifted from one cantilever to another while remaining substantially in focus. One of the focusing lenses can be mounted in close proximity to the cantilever to provide a high numerical aperture. An optional adjustable lens can also be mounted on the module. A piezoelectric tapping element can be embedded in a base plate of the cantilever module for tapping mode AFM.

23 Claims, 5 Drawing Sheets

